

520.43079X00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: TANAKA, et al.

Filed: August 27, 2003

For: SYSTEM AND METHOD FOR EVALUATING A SEMICONDUCTOR
DEVICE PATTERN, METHOD FOR CONTROLLING PROCESS OF
FORMING A SEMICONDUCTOR DEVICE PATTERN AND METHOD
FOR MONITORING A SEMICONDUCTOR DEVICE
MANUFACTURING PROCESS

CLAIM FOR PRIORITY

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

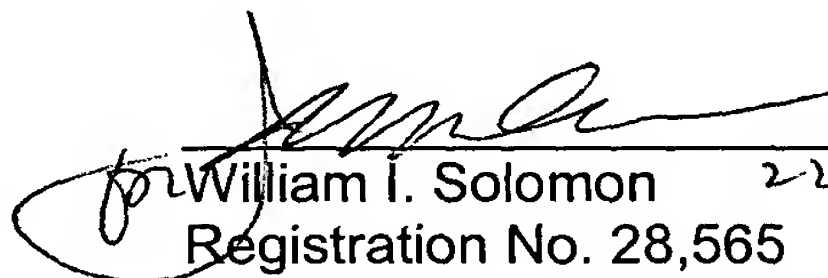
August 27, 2003

Sir:

Under the provisions of 35 USC §119 AND 37 CFR § 1.55, Applicants hereby
claim the right of priority based on Patent Application No. 2003-033522 filed in Japan
on February 12, 2003.

Respectfully submitted,

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